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Application Number	10/042,924
Filing Date	January 9, 2002
First Named Inventor	Forbes, Leonard
Group Art Unit	2813
Examiner Name	Vesperman, William

Attorney Docket No: 303.684US2

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	First Named Inventor	Forbes, Leonard		
	Group Art Unit	2813		
4. 2004 SJ	Examiner Name	Vesperman, William		
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	record	Filing Date	January 9, 2002
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1	JUH U PUR	Examiner Name	Vesperman, William
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